Christian A Zorman

List of Publications by Citations

168	4,901	34	66
papers	citations	h-index	g-index
183	5,524	3.9	5.44
ext. papers	ext. citations	avg, IF	L-index

#	Paper	IF	Citations
168	Nanoelectromechanical systems: Nanodevice motion at microwave frequencies. *Nature*, **2003**, 421, 496	50.4	438
167	Evaluation of MEMS materials of construction for implantable medical devices. *Biomaterials*, **2002**, 23, 2737-50	15.6	361
166	Silicon carbide MEMS for harsh environments. *Proceedings of the IEEE*, **1998**, 86, 1594-1609	14.3	320
165	Polytype control of spin qubits in silicon carbide. *Nature Communications*, **2013**, 4, 1819	17.4	229
164	Monocrystalline silicon carbide nanoelectromechanical systems. *Applied Physics Letters*, **2001**, 78, 162-164	3.4	223
163	SiC MEMS: opportunities and challenges for applications in harsh environments. *Thin Solid Films*, **1999**, 355-356, 518-524	2.2	219
162	Epitaxial growth of 3C-SiC films on 4 in. diam (100) silicon wafers by atmospheric pressure chemical vapor deposition. *Journal of Applied Physics*, **1995**, 78, 5136-5138	2.5	206
161	High-temperature single-crystal 3C-SiC capacitive pressure sensor. *IEEE Sensors Journal*, **2004**, 4, 464-470	4	157
160	Low voltage nanoelectromechanical switches based on silicon carbide nanowires. *Nano Letters*, **2010**, 10, 2891-6	11.5	133
159	Wearable sensors for monitoring the physiological and biochemical profile of the athlete. *Npj Digital Medicine*, **2019**, 2, 72	15.7	128
158	Silicon carbide for microelectromechanical systems. *International Materials Reviews*, **2000**, 45, 85-108	16.1	113
157	Electrothermal tuning of AlN-SiC nanomechanical resonators. *Nanotechnology*, **2006**, 17, 1506-1511	3.4	88
156	Micro- and nanomechanical structures for silicon carbide MEMS and NEMS. *Physica Status Solidi (B): Basic Research*, **2008**, 245, 1404-1424	1.3	81
155	Fabrication and testing of bulk micromachined silicon carbide piezoresistive pressure sensors for high temperature applications. *IEEE Sensors Journal*, **2006**, 6, 316-324	4	79
154	Wearable sensors for monitoring the internal and external workload of the athlete. *Npj Digital Medicine*, **2019**, 2, 71	15.7	75
153	Mechanically adaptive nanocomposites for neural interfacing. *MRS Bulletin*, **2012**, 37, 581-589	3.2	75
152	Quantitative evaluation of biaxial strain in epitaxial 3C-SiC layers on Si(100) substrates by Raman spectroscopy. *Journal of Applied Physics*, **2002**, 91, 1113-1117	2.5	71

151	Examination of Bulge Test for Determining Residual Stress, Young Modulus, and Poisson Ratio of 3C-SiC Thin Films. *Journal of Aerospace Engineering*, **2003**, 16, 46-54	1.4	65
150	Deposition of Polycrystalline 3C-SiC Films on 100 mm Diameter Si(100) Wafers in a Large-Volume LPCVD Furnace. *Electrochemical and Solid-State Letters*, **2002**, 5, G99		57
149	Fabrication and testing of micromachined silicon carbide and nickel fuel atomizers for gas turbine engines. *Journal of Microelectromechanical Systems*, **1999**, 8, 251-257	2.5	57
148	Pendeo-epitaxial growth of thin films of gallium nitride and related materials and their characterization. *Journal of Crystal Growth*, **2001**, 225, 134-140	1.6	56
147	SiC cantilever resonators with electrothermal actuation. *Sensors and Actuators A: Physical*, **2006**, 128, 376-386	3.9	50
146	. *IEEE Transactions on Electron Devices*, **2002**, 49, 2323-2332	2.9	49
145	Fabrication and testing of surface micromachined polycrystalline SiC micromotors. *IEEE Electron Device Letters*, **2000**, 21, 164-166	4.4	49
144	Tuning Optical Signatures of Single- and Few-Layer MoS by Blown-Bubble Bulge Straining up to Fracture. *Nano Letters*, **2017**, 17, 4568-4575	11.5	45
143	Use of deposition pressure to control residual stress in polycrystalline SiC films. *Applied Physics Letters*, **2004**, 84, 341-343	3.4	45
142	Characterization of polycrystalline silicon carbide films grown by atmospheric pressure chemical vapor deposition on polycrystalline silicon. *Journal of Materials Research*, **1998**, 13, 406-412	2.5	43
141	Polycrystalline 3C-SiC thin films deposited by dual precursor LPCVD for MEMS applications. *Sensors and Actuators A: Physical*, **2005**, 119, 169-176	3.9	42
140	Mechanical properties of epitaxial 3C silicon carbide thin films. *Journal of Microelectromechanical Systems*, **2005**, 14, 664-672	2.5	40
139	Femtosecond pulsed laser micromachining of single crystalline 3C SiC structures based on a laser-induced defect-activation process. *Journal of Micromechanics and Microengineering*, **2003**, 13, 680-685	2	39
138	Measurement of residual stress and elastic modulus of polycrystalline 3C-SiC films deposited by low-pressure chemical vapor deposition. *Thin Solid Films*, **2005**, 492, 195-202	2.2	37
137	Surface micromachining of polycrystalline SiC films using microfabricated molds of SiO/sub 2/ and polysilicon. *Journal of Microelectromechanical Systems*, **1999**, 8, 237-242	2.5	37
136	Fabrication of electrically conductive metal patterns at the surface of polymer films by microplasma-based direct writing. *ACS Applied Materials & Interfaces*, **2014**, 6, 3099-104	9.5	36
135	Characterization of frequency tuning using focused ion beam platinum deposition. *Journal of Micromechanics and Microengineering*, **2007**, 17, 213-219	2	34
134	Stable secondary electron emission observations from chemical vapor deposited diamond. *Applied Physics Letters*, **1994**, 65, 2702-2704	3.4	33

133	Review□Inkjet Printing of Metal Structures for Electrochemical Sensor Applications. *Journal of the Electrochemical Society*, **2020**, 167, 037571	3.9	32
132	The mechanical properties of polycrystalline 3C-SiC films grown on polysilicon substrates by atmospheric pressure chemical-vapor deposition. *Journal of Applied Physics*, **2006**, 99, 044108	2.5	32
131	Conventional and pendeo-epitaxial growth of GaN(0001) thin films on Si(111) substrates. *Journal of Crystal Growth*, **2001**, 231, 335-341	1.6	32
130	Stable secondary electron emission from chemical vapor deposited diamond films coated with alkali-halides. *Applied Physics Letters*, **1995**, 66, 242-244	3.4	30
129	Mechanical properties of a 3C-SiC film between room temperature and 600 □C. *Journal Physics D: Applied Physics*, **2007**, 40, 3335-3342	3	29
128	Mid-infrared metamaterial based on perforated SiC membrane: engineering optical response using surface phonon polaritons. *Applied Physics A: Materials Science and Processing*, **2007**, 88, 605-609	2.6	27
127	Surface Micromachining of Polycrystalline SiC Deposited on SiO2 by APCVD. *Materials Science Forum*, **1998**, 264-268, 885-888	0.4	27
126	. *Journal of Microelectromechanical Systems*, **2011**, 20, 867-875	2.5	25
125	Synthesis of Wide Bandgap □Ga2O3 Rods on 3C-SiC-on-Si. *Crystal Growth and Design*, **2016**, 16, 511-517	3.5	24
124	Ultrawide Band Gap □GaO Nanomechanical Resonators with Spatially Visualized Multimode Motion. *ACS Applied Materials & Interfaces*, **2017**, 9, 43090-43097	9.5	23
123	Etching of 3C-SiC using CHF3/O2 and CHF3/O2/He plasmas at 1.75 Torr. *Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena*, **1998**, 16, 536		23
122	Origin of the split Si□H stretch mode on hydrogen terminated 6H-SiC(0001): Titration of crystal truncation. *Applied Physics Letters*, **2002**, 80, 4726-4728	3.4	22
121	Micro/Nanotribological Studies of Single-Crystal Silicon and Polysilicon and SiC Films for Use in MEMS Devices **1998**, 407-430		21
120	Fabrication of low defect density 3C-SiC on SiO2 structures using wafer bonding techniques. *Journal of Electronic Materials*, **1998**, 27, L17-L20	1.9	19
119	Performance of 3C-SiC thin films as protective coatings for silicon-micromachined atomizers. *Thin Solid Films*, **1998**, 315, 170-178	2.2	19
118	Pendeo-epitaxial growth of gallium nitride on silicon substrates. *Journal of Electronic Materials*, **2000**, 29, 306-310	1.9	19
117	Atmospheric-Pressure Plasma Reduction of Metal Cation-Containing Polymer Films to Produce Electrically Conductive Nanocomposites by an Electrodiffusion Mechanism. *Plasma Chemistry and Plasma Processing*, **2016**, 36, 295-307	3.6	18
116	Development of Nickel Wire Bonding for High-Temperature Packaging of SiC Devices. *IEEE Transactions on Advanced Packaging*, **2009**, 32, 564-574		18

115	Polycrystalline silicon-carbide surface-micromachined vertical resonators-part II: electrical testing and material property extraction. *Journal of Microelectromechanical Systems*, **2005**, 14, 579-589	2.5	18
114	A New Class of Low-Temperature Plasma-Activated, Inorganic Salt-Based Particle-Free Inks for Inkjet Printing Metals. *Advanced Materials Technologies*, **2019**, 4, 1900119	6.8	17
113	Silicon carbide MEMS-resonator-based oscillator. *Journal of Micromechanics and Microengineering*, **2009**, 19, 115027	2	17
112	Development of a Multilayer SiC Surface Micromachining Process with Capabilities and Design Rules Comparable to Conventional Polysilicon Surface Micromachining. *Materials Science Forum*, **2002**, 389-393, 755-758	0.4	17
111	Molecular conformation and filtration properties of anionic Ficoll. *American Journal of Physiology - Renal Physiology*, **2010**, 299, F752-7	4.3	16
110	Roughness Reduction of 3C-SiC Surfaces Using SiC-Based Mechanical Polishing Slurries. *Journal of the Electrochemical Society*, **1999**, 146, 327-330	3.9	16
109	Plasmas for additive manufacturing. *Plasma Processes and Polymers*, **2020**, 17, 2000009	3.4	15
108	An oversampled capacitance-to-voltage converter IC with application to time-domain characterization of MEMS resonators. *IEEE Sensors Journal*, **2005**, 5, 1353-1361	4	15
107	Vascular Pressure-Flow Measurement Using CB-PDMS Flexible Strain Sensor. *IEEE Transactions on Biomedical Circuits and Systems*, **2019**, 13, 1451-1461	5.1	14
106	Basal lamina secreted by MDCK cells has size- and charge-selective properties. *American Journal of Physiology - Renal Physiology*, **2011**, 300, F86-90	4.3	14
105	Low Stress Polycrystalline SiC Thin Films Suitable for MEMS Applications. *Journal of the Electrochemical Society*, **2011**, 158, H675	3.9	14
104	Amorphous SiC as a structural layer in microbridge-based RF MEMS switches for use in software-defined radio. *Solid-State Electronics*, **2008**, 52, 1647-1651	1.7	14
103	Microplasma-Induced in Situ Formation of Patterned, Stretchable Electrical Conductors. *ACS Macro Letters*, **2017**, 6, 194-199	6.6	13
102	Electrically Conductive, Reduced Graphene Oxide Structures Fabricated by Inkjet Printing and Low Temperature Plasma Reduction.. *Advanced Materials Technologies*, **2019**, 4, 1900834	6.8	13
101	Deep level defects and carrier removal due to proton and alpha particle irradiation of InP. *Journal of Applied Physics*, **1994**, 75, 3187-3189	2.5	13
100	Transfer printing of self-folding polymer-metal bilayer particles. *ACS Applied Materials & Interfaces*, **2014**, 6, 22695-700	9.5	12
99	Electrically small folded slot antenna utilizing capacitive loaded slot lines **2008**,		12
98	Polycrystalline silicon-carbide surface-micromachined vertical resonators-part I: growth study and device fabrication. *Journal of Microelectromechanical Systems*, **2005**, 14, 567-578	2.5	12

97	. *Journal of Physics Condensed Matter*, **2000**, 12, 10175-10183	1.8	12
96	Electric Field Patterning of Organic Nanoarchitectures with Self-Assembled Molecular Fibers. *Journal of Physical Chemistry C*, **2008**, 112, 12081-12084	3.8	11
95	Fabrication of Suspended Nanomechanical Structures from Bulk 6H-SiC Substrates. *Materials Science Forum*, **2004**, 457-460, 1531-1536	0.4	11
94	Chemical Mechanical Polishing of Cubic Silicon Carbide Films Grown on Si(100) Wafers. *Journal of the Electrochemical Society*, **2002**, 149, G643	3.9	11
93	Nanoparticle based simple electrochemical biosensor platform for profiling of protein-nucleic acid interactions. *Talanta*, **2019**, 195, 46-54	6.2	11
92	The influence of impurities and planar defects on the infrared properties of silicon carbide films. *Applied Physics Letters*, **2011**, 98, 191904	3.4	10
91	Non-hermetic packaging of biomedical microsystems from a materials perspective: A review. *Medical Devices & Sensors*, **2020**, 3, e10082	1.6	9
90	RF MEMS switches with sic microbridges for improved reliability **2008**,		9
89	Surface Roughness Control of 3C-SiC Films during the Epitaxial Growth Process. *Journal of the Electrochemical Society*, **2004**, 151, G910	3.9	9
88	Synthesis and characterization of Ga2O3 nanosheets on 3C-SiC-on-Si by low pressure chemical vapor deposition. *Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics*, **2017**, 35, 011208	1.3	8
87	Tunable resistivity in ink-jet printed electrical structures on paper by plasma conversion of particle-free, stabilizer-free silver inks. *Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films*, **2018**, 36, 051302	2.9	8
86	Microscale Characterization of a Mechanically Adaptive Polymer Nanocomposite With Cotton-Derived Cellulose Nanocrystals for Implantable BioMEMS. *Journal of Microelectromechanical Systems*, **2014**, 23, 774-784	2.5	8
85	Adhesion and Moisture Barrier Characteristics of Roller-Cast Polydimethylsiloxane Encapsulants for Implantable Microsystems. *Proceedings of IEEE Sensors*, **2012**, 2012, 1-4	0	8
84	Electrical Characterization of Microelectromechanical Silicon Carbide Resonators. *Sensors*, **2008**, 8, 5759-5774	3.8	8
83	Fabrication of a Silver-Based Thermistor on Flexible, Temperature-Sensitive Substrates Using a Low-Temperature Inkjet Printing Technique **2019**, 3,		7
82	$beta$ -Ga2O3 NEMS Oscillator for Real-Time Middle Ultraviolet (MUV) Light Detection. *IEEE Electron Device Letters*, **2018**, 39, 1230-1233	4.4	7
81	Grain size control of (111) polycrystalline 3C-SiC films by doping used as folded-beam MEMS resonators for energy dissipation. *Microsystem Technologies*, **2009**, 15, 875-880	1.7	7
80	Determination of Young moduli of 3C (110) single-crystal and (111) polycrystalline silicon carbide from operating frequencies. *Journal of Materials Science*, **2008**, 43, 4512-4517	4.3	7

79	Electrostatically Driven Touch-Mode Poly-SiC Microspeaker **2007**,		7
78	Surface Micromachining: A Brief Introduction. *MRS Bulletin*, **2001**, 26, 289-290	3.2	7
77	Polycrystalline Diamond-on-Polymer Electrode Arrays Fabricated Using a Polymer-Based Transfer Process. *Electrochemical and Solid-State Letters*, **2010**, 13, J129		6
76	Behaviour of Polycrystalline SiC and Si Surface-Micromachined Lateral Resonant Structures at Elevated Temperatures. *Materials Science Forum*, **1998**, 264-268, 889-894	0.4	6
75	Growth of polycrystalline SiC films on SiO 2 and Si 3 N 4 by APCVD. *Thin Solid Films*, **1999**, 355-356, 179-183	2.1	6
74	Wireless Bladder Pressure Monitor for Closed-Loop Bladder Neuromodulation. *Proceedings of IEEE Sensors*, **2016**, 2016,	0	6
73	Vascular Graft Pressure-Flow Monitoring Using 3D Printed MWCNT-PDMS Strain Sensors. *Annual International Conference of the IEEE Engineering in Medicine and Biology Society IEEE Engineering in Medicine and Biology Society Annual International Conference*, **2018**, 2018, 2989-2992	0.9	6
72	Direct, Transfer-Free Growth of Large-Area Hexagonal Boron Nitride Films by Plasma-Enhanced Chemical Film Conversion (PECFC) of Printable, Solution-Processed Ammonia Borane. *ACS Applied Materials & Interfaces*, **2018**, 10, 43936-43945	9.5	6
71	Environmentally-controlled microtensile testing of mechanically-adaptive polymer nanocomposites for ex vivo characterization. *Journal of Visualized Experiments*, **2013**, e50078	1.6	5
70	Removal of endotoxin from deionized water using micromachined silicon nanopore membranes. *Journal of Micromechanics and Microengineering*, **2011**, 21, 054029	2	5
69	Amorphous Silicon Carbide as a Non-Biofouling Structural Material for Biomedical Microdevices. *Materials Science Forum*, **2012**, 717-720, 537-540	0.4	5
68	Amorphous Silicon Carbide (a-SiC) Thin Square Membranes for Resonant Micromechanical Devices. *Materials Science Forum*, **2012**, 717-720, 533-536	0.4	5
67	Development of a Microfabricated Flat Interface Nerve Electrode Based on Liquid Crystal Polymer and Polynorbornene Multilayered Structures **2007**,		5
66	Fabrication and Characterization of Flexible, Microfabricated Neural Electrode Arrays Made from Liquid Crystal Polymer and Polynorbornene. *Materials Research Society Symposia Proceedings*, **2006**, 926, 1		5
65	PECVD Silicon Carbide as a Chemically-Resistant Thin Film Packaging Technology for Microfabricated Antennas **2006**,		5
64	Development of PECVD SiC for MEMS Using 3MS as the Precursor. *Materials Research Society Symposia Proceedings*, **2006**, 911, 28		5
63	Characterization of Polycrystalline SiC Thin Films for MEMS Applications using Surface Micromachined Devices. *Materials Science Forum*, **2004**, 457-460, 1523-1526	0.4	5
62	Composition and physical properties of thin a-C:N and a-C:N:H films deposited by ion beam techniques. *Surface and Interface Analysis*, **1994**, 21, 95-100	1.5	5

61	Synthesis and Characterization of Nitrogen Containing Diamondlike Carbon Films made by ion Beam Deposition. *Materials Research Society Symposia Proceedings*, **1994**, 349, 465		5
60	Probing heavy ion radiation effects in silicon carbide (SiC) via 3D integrated multimode vibrating diaphragms. *Applied Physics Letters*, **2019**, 114, 101901	3.4	4
59	High frequency torsional-mode nanomechanical resonators enabled by very thin nanocrystalline diamond diaphragms. *Diamond and Related Materials*, **2015**, 54, 19-25	3.5	4
58	Materials Aspects of Micro- and Nanoelectromechanical Systems. *Springer Handbooks*, **2017**, 163-190	1.3	4
57	Young's Modulus and Residual Stress of Polycrystalline 3C-SiC Films Grown by LPCVD and Measured by the Load-Deflection Technique. *Materials Science Forum*, **2004**, 457-460, 1519-1522	0.4	4
56	Advanced Processing Techniques for Silicon Carbide MEMS and NEMS. *Materials Science Forum*, **2004**, 457-460, 1451-1456	0.4	4
55	Far-field detection of the super-lensing effect in the mid-infrared: theory and experiment. *Journal of Modern Optics*, **2005**, 52, 2351-2364	1.1	4
54	On the stability of ?-SiC with respect to chemical disorder induced by irradiation with energetic particles. *Philosophical Magazine Letters*, **2001**, 81, 55-61	1	4
53	High-energy femtosecond pulsed laser micromachining of thin film deposited silicon in self-focused air medium. *Journal of Laser Applications*, **2002**, 14, 221-229	2.1	4
52	Inkjet-Printed Hydrogen Peroxide Sensor With Sensitivity Enhanced by Plasma Activated Inorganic Metal Salt Inks. *Journal of Microelectromechanical Systems*, **2020**, 29, 1026-1031	2.5	4
51	A Programmable Sustaining Amplifier for Flexible Multimode MEMS-Referenced Oscillators. *IEEE Transactions on Circuits and Systems I: Regular Papers*, **2019**, 66, 1405-1418	3.9	4
50	3C-SiC microdisk mechanical resonators with multimode resonances at radio frequencies. *Journal of Micromechanics and Microengineering*, **2017**, 27, 074001	2	3
49	Free-Standing Ga2O3 Thin Diaphragms. *Journal of Electronic Materials*, **2018**, 47, 973-981	1.9	3
48	Development of an integrated surface stimulation device for systematic evaluation of wound electrotherapy. *Annals of Biomedical Engineering*, **2015**, 43, 306-13	4.7	3
47	Development of polynorbornene as a structural material for microfluidics and flexible BioMEMS. *Journal of Applied Polymer Science*, **2014**, 131, n/a-n/a	2.9	3
46	A polycrystalline SiC-on-Si architecture for capacitive pressure sensing applications beyond 400 C: Process development and device performance. *Journal of Materials Research*, **2013**, 28, 120-128	2.5	3
45	PVD silicon carbide as a thin film packaging technology for antennas on LCP substrates for harsh environments **2010**,		3
44	Additive Processes for Semiconductors and Dielectric Materials. *MEMS Reference Shelf*, **2011**, 37-136		3

43	New developments in MEMS using SiC and TiNi shape memory alloy materials. *Current Opinion in Solid State and Materials Science*, **1997**, 2, 566-570	12	3
42	Effects of biomedical sterilization processes on performance characteristics of MEMS pressure sensors. *Biomedical Microdevices*, **2007**, 9, 809-14	3.7	3
41	Fabrication of hall device structures in 3C-SiC using microelectromechanical processing technology. *Microelectronic Engineering*, **2006**, 83, 1396-1399	2.5	3
40	Nitrogen-Doping of Polycrystalline 3C-SiC Films Deposited by Low Pressure Chemical Vapor Deposition. *Materials Science Forum*, **2006**, 527-529, 311-314	0.4	3
39	Low Temperature A-SiC/Si Direct Bonding Technology for MEMS/NEMS **2007**,		3
38	PECVD Silicon Carbide as a Thin Film Packaging Material for Microfabricated Neural Electrodes. *Materials Research Society Symposia Proceedings*, **2007**, 1009, 1		3
37	A system to measure minute hydraulic permeability of nanometer scale devices in a non-destructive manner. *Measurement Science and Technology*, **2011**, 22, 045802	2	3
36	Electrical interfaces for recording, stimulation, and sensing **2015**, 13-38		2
35	Wireless capacitive pressure sensor operating up to 400□c from 0 to 100 psi utilizing power scavenging **2014**,		2
34	Correlating charge fluence with nanoparticle formation during in situ plasma synthesis of nanocomposite films. *Plasma Processes and Polymers*, **2017**, 14, 1700079	3.4	2
33	Energetic ion radiation effects on a silicon carbide (SiC) multimode resonating diaphragm **2017**,		2
32	Pressure dependence of thin polycrystalline silicon carbide diaphragm resonators **2012**,		2
31	Temperature dependence of SiC thin film metal-insulator-metal (MIM) capacitors on alumina over a temperature range from 25 to 500□C **2011**,		2
30	Focused Ion-Beam (FIB) Nanomachining of Silicon Carbide (SiC) Stencil Masks for Nanoscale Patterning. *Materials Science Forum*, **2012**, 717-720, 889-892	0.4	2
29	Energy Dissipation in Folded-Beam MEMS Resonators Made from Single Crystal and Polycrystalline 3C-SiC Films **2007**,		2
28	Development of amorphous SiC for MEMS-based microbridges **2007**,		2
27	Spatial Uniformity of the Mechanical Properties of 3C-SiC Films Grown on 4-Inch Si Wafers as a Function of Film Growth Conditions. *Materials Science Forum*, **1998**, 264-268, 635-640	0.4	2
26	Determination of Elastic Modulus of Silicon Carbide (SiC) Thin Diaphragms via Mode-Dependent Duffing Nonlinear Resonances. *Journal of Microelectromechanical Systems*, **2020**, 29, 783-789	2.5	2

25	Engineering the surface morphology of inkjet printed Ag by controlling solvent evaporation during plasma conversion of AgNO3 inks. *Journal of Materials Chemistry C*, **2022**, 10, 5257-5265	7.1	2
24	Wide bandgap Ga2O3 nanomechanical resonators for detection of middle-ultraviolet (MUV) photon radiation **2017**,		1
23	Demonstration of a Packaged Capacitive Pressure Sensor System Suitable for Jet Turbofan Engine Health Monitoring **2016**,		1
22	Doped polycrystalline 3C-SiC films with low stress for MEMS: part II. Characterization using micromachined structures. *Journal of Micromechanics and Microengineering*, **2014**, 24, 065001	2	1
21	Doped polycrystalline 3CSiC films with low stress for MEMS: part I. Deposition conditions and film properties. *Journal of Micromechanics and Microengineering*, **2014**, 24, 035013	2	1
20	Diaphragm-based microsystems using thin film silicon carbide **2012**,		1
19	Fabrication and Characterization of MEMS-Based Structures from a Bio-Inspired, Chemo-Responsive Polymer Nanocomposite. *Materials Research Society Symposia Proceedings*, **2011**, 1299, 1		1
18	A low-cost automated streaming potential measurement system. *Journal of the Association for Laboratory Automation*, **2012**, 17, 125-33		1
17	A Polynorbornene-Based Microelectrode Array for Neural Interfacing **2007**,		1
16	Silicon carbide micro- and nanoelectromechanical systems **2004**,		1
15	Finite-Element Modeling of Residual Stress in SiC Diaphragms. *Materials Research Society Symposia Proceedings*, **1998**, 518, 221		1
14	DEPOSITION TECHNIQUES FOR SIC MEMS **2006**, 18-45		1
13	Packaged capacitive pressure sensor system for aircraft engine health monitoring **2016**,		1
12	Mechanical Properties and Morphology of Polycrystalline 3C-SiC Films Deposited on Si and SiO2 by LPCVD. *Materials Research Society Symposia Proceedings*, **2003**, 795, 140		0
11	An improved tactile sensing device for material characterization via friction-induced vibrations. *Sensors and Actuators A: Physical*, **2020**, 303, 111824	3.9	
10	Contactless radio frequency probes for high-temperature characterisation of microwave integrated circuits. *Electronics Letters*, **2014**, 50, 817-819	1.1	
9	Material Aspects of Micro- and Nanoelectromechanical Systems **2010**, 333-356		
8	Silicon Carbide BioMEMS **2012**, 351-376		

List of Publications

7	Material Aspects of Micro- and Nanoelectromechanical Systems **2007**, 299-322	
6	Novel Polycrystalline SiC Films Containing Nanoscale Through-Pores by Selective APCVD. *Materials Science Forum*, **2006**, 527-529, 755-758	0.4
5	Characterization of Low Stress, Undoped LPCVD Polycrystalline SiC Films for MEMS Applications. *Materials Science Forum*, **2006**, 527-529, 1103-1106	0.4
4	A Novel Method of Fabricating SiC-On-Insulator Substrates for Use in MEMS. *Materials Research Society Symposia Proceedings*, **2001**, 681, 1	
3	Micro- and Nanomechanical Structures for Silicon Carbide MEMS and NEMS411-451	
2	Wireless Monitoring of Vascular Pressure Using CB-PDMS Based Flexible Strain Sensor. *Annual International Conference of the IEEE Engineering in Medicine and Biology Society IEEE Engineering in Medicine and Biology Society Annual International Conference*, **2021**, 2021, 7011-7015	0.9
1	An Absorbent, Flexible, Transparent, and Scalable Substrate for Wound Dressings. *IEEE Journal of Translational Engineering in Health and Medicine*, **2022**, 1-1	3